



Session Title:	[TuG2] Frontier Metrology and Modeling II
Session Date:	November 12 (Tue.), 2024
Session Time:	15:00-17:00
Session Room:	Room G (Meeting Room, 5F, Grand Josun Busan)
Session Chair:	Prof. Tae-Hun Shim (Hanyang Univ., Korea)

[TuG2-1] [Invited] 15:00-15:30

Bridging the Gap: From Surface Topography to Semiconductor Applications with ISE and AFM

Dang Quang Nquyen, Geonwoo Kim, Seungmin Park, Mangesh Diware, and Sang-Joon Cho
(Park Systems Corp., Korea)

[TuG2-2] [Invited] 15:30-16:00

Multiscale Simulation and AI-Driven Approaches for Comprehensive Understanding of Advanced Materials and Semiconductor Processing

Sung Beom Cho (Ajou Univ., Korea)

[TuG2-3] [Invited] 16:00-16:30

Recent Progress of Display and Semiconductor Inspection Using FSH (Flying-over Scanning Holography)

Taegeun Kim (Cubixel Co., Ltd., Korea)

[TuG2-4] [Invited] 16:30-17:00

Nanoscale and Interfacial Physical Characterization for Supporting Memory Device Manufacturing

Jae-Hyun Kim (SK hynix Inc., Korea)